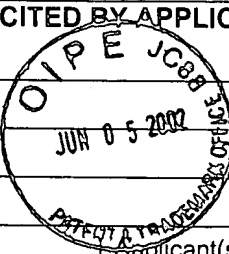


U.S. Department of Commerce, Patent and Trademark Office (PTO Form 1449 modified)					Docket No. APPM/4714.D1	Serial No. 09/625,336	
LIST OF PATENTS AND PUBLICATIONS CITED BY APPLICANT					Applicant Kori, et al.	Confirmation No. 7523	
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*Examiner Initial	Document Number	Issue Date	Applicant(s) Name	Class	Subclass	Filing Date If Appropriate
<i>mu</i>	A1	2001/0042799	Kim, et al.	239	553	02/02/2001
	A2					
	A3					
	A4					
	A5					
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	A7					
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	B2					<input type="checkbox"/>	<input type="checkbox"/>

OTHER ART

*Examiner Initial	Including Author, Title, Date, Pertinent Pages, Etc.
<i>mu</i>	C1 "Cluster Tools for Fabrication of Advanced Devices" Jap. J. of Applied Physics, Extended Abstracts 22 nd Conference Solid State Devices and Materials (1999), pp. 849- 852
<i>mu</i>	C2 Kitigawa, et al., "Hydrogen-mediated low temperature epitaxy of Si in plasma-enhanced chemical vapor deposition", Applied Surface Science (2000), pp. 30-34
	C3 Lee, et al., "Pulsed nucleation for ultra-high aspect ratio tungsten plugfill", Novellus Systems, Inc. (2001), pp. 1-2 (COPY NOT AVAILABLE TO APPLICANT AT THIS TIME)

Examiner *Rudol* Date Considered *7/9/02*

***EXAMINER:** Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.